IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Robert Baxter Chambers II. et al.

Art Unit: 2456

Serial No.: 10/617.551

7 Ht Omt. 2430

Filed: July 11, 2003

Examiner: Nguyen, Van Kim T.

For: METHODS AND SYSTEMS FOR MANAGING AND CONTROLLING

AN AUTOMATION CONTROL

MODULE SYSTEM

Mail Stop Issue Fee Commissioner for Patents

P.O. Box 1450 Alexandria, VA 22313

COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE

The following comments are in response to the Examiner's Statement of Reasons for Allowance in the Notice of Allowability dated December 28, 2010.

Applicants respectfully disagree with the Examiner's Statement of Reasons for Allowance because such statements may have unintentionally introduced some ambiguities in what was otherwise a very concise and thorough examination of the claims of this patent application. While Applicants believe that the claims are allowable, Applicants do not acquiesce that patentability resides in the features paraphrased in the Examiner's Statement of Reasons for Allowance.

Also, reasons for allowance are only warranted in instances in which the record of the prosecution as a whole does not make clear the Examiner's reasons for allowing a claim or claims (see 37 CFR §1.104(e)). In the present patent application, Applicants believe the record as a whole makes the reasons for allowance clear and therefore no statement by the Examiner is necessary or warranted.

Respectfully submitted,

Patrick W. Rasche

Registration No. 37,916 ARMSTRONG TEASDALE LLP 7700 Forsyth Blvd., Suite 1800 St. Louis, Missouri 63105

(314) 621-5070